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United States Patent [19]

Koizumi

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[54] **CHAMBER FOR SEMICONDUCTOR FABRICATING MACHINE**

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[73] Assignee: **Canon Kabushiki Kaisha**, Tokyo, Japan

[**] Term: **14 Years**

[21] Appl. No.: **676,068**

[22] Filed: **Mar. 27, 1991**

[30] **Foreign Application Priority Data**

Oct. 3, 1990 [JP] Japan 2-33476

[52] **U.S. Cl.** **D15/199**

[58] **Field of Search** D15/199; 29/593, 714, 29/739, 845, 848; 198/204, 127, 264, 213, 160, 37, 739, 714; 357/23.4, 49, 65, 67, 70, 71, 72; 428/620, 632, 634; 437/62, 89, 99; 148/DIG. 12; 118/50.1, 725; 219/411

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[57] **CLAIM**

The ornamental design for a chamber for semiconductor fabricating machine, as shown and described.

DESCRIPTION

FIG. **1** is a front elevational view of a chamber for semiconductor fabricating machine showing my new design;
FIG. **2** is a rear elevational view thereof;
FIG. **3** is a top plan view thereof;
FIG. **4** is a bottom plan view thereof;
FIG. **5** is a left side elevational view thereof;
FIG. **6** is a right side elevational view thereof; and,
FIG. **7** is a perspective view thereof.

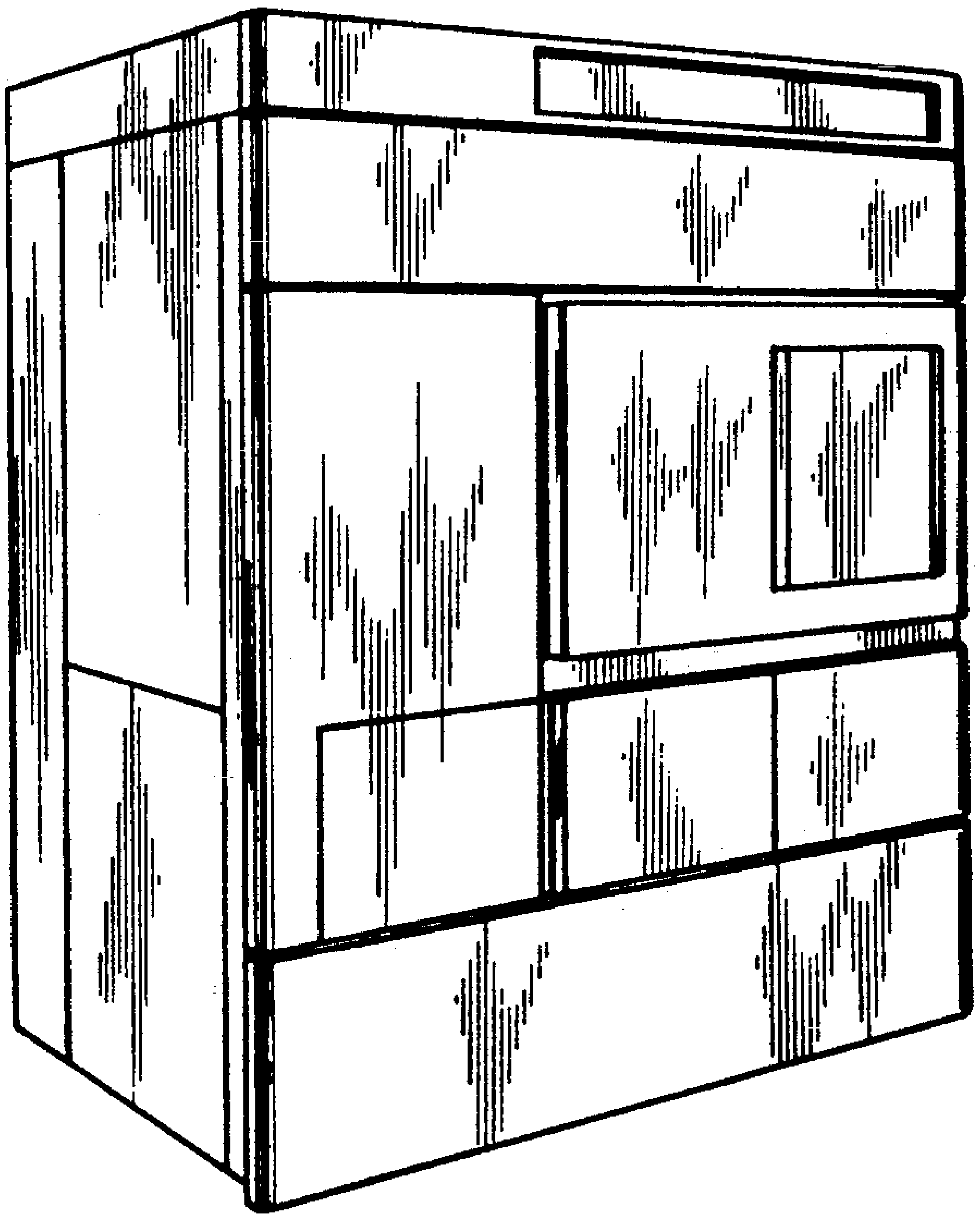

FIG. 1

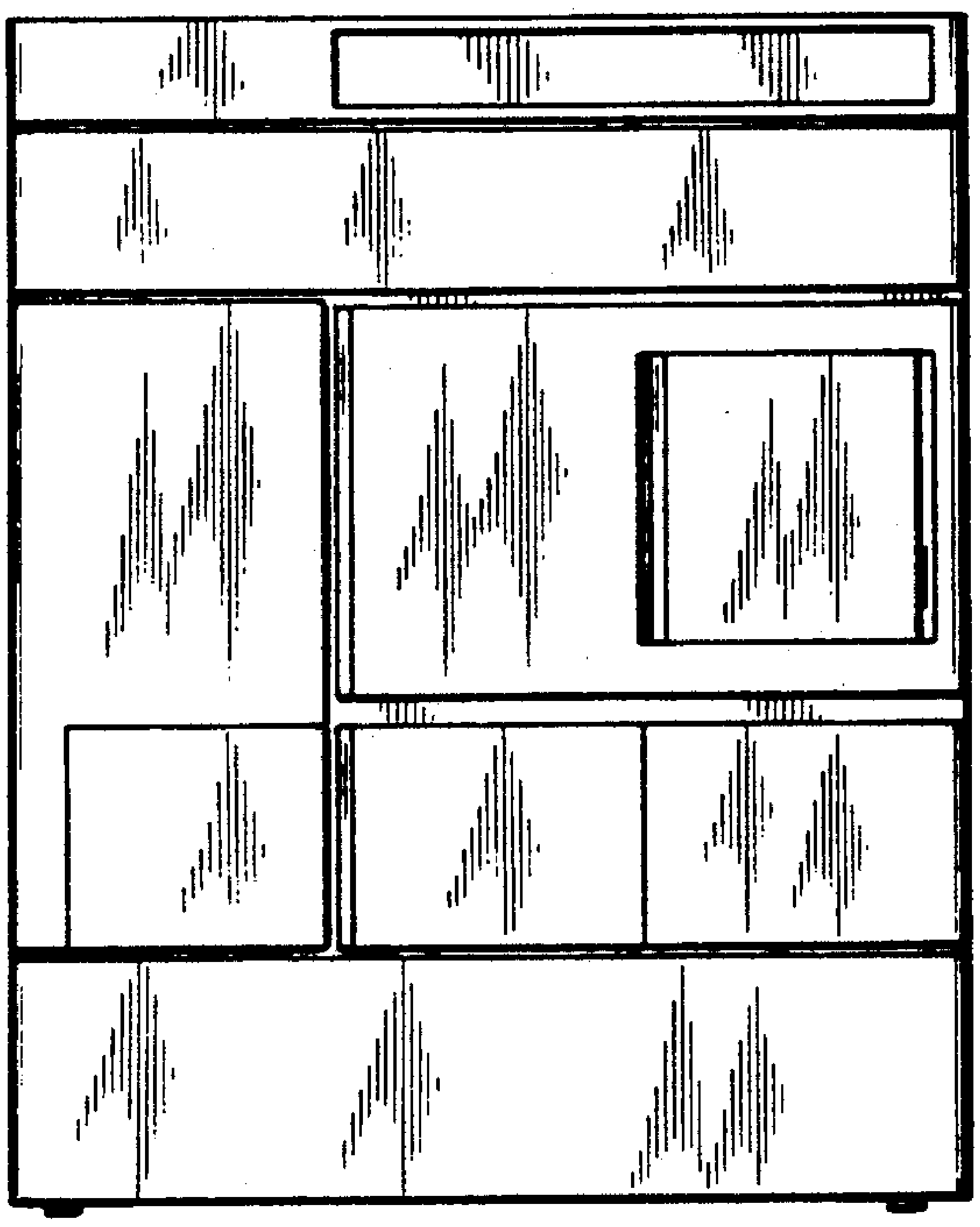

FIG. 2

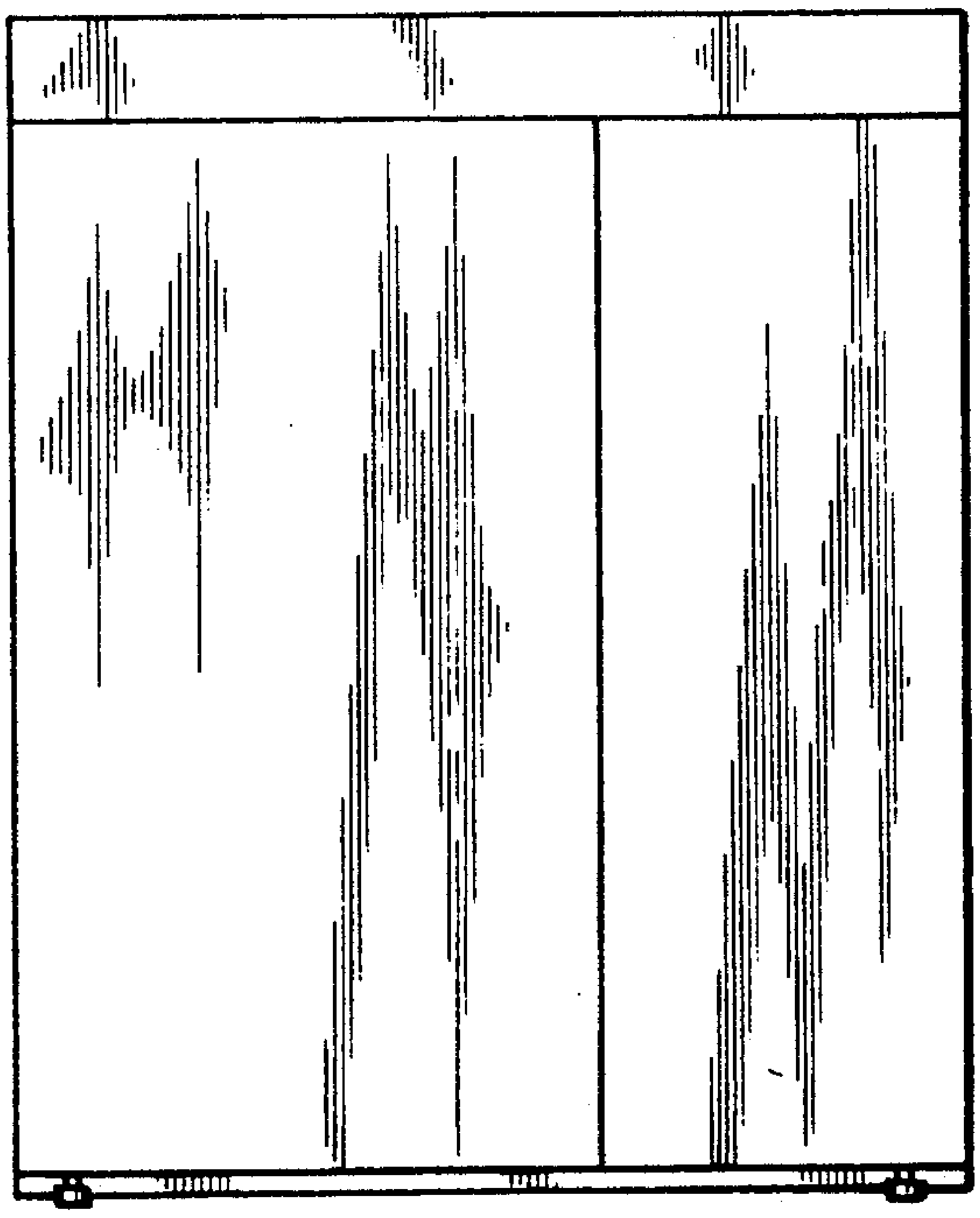

FIG. 3

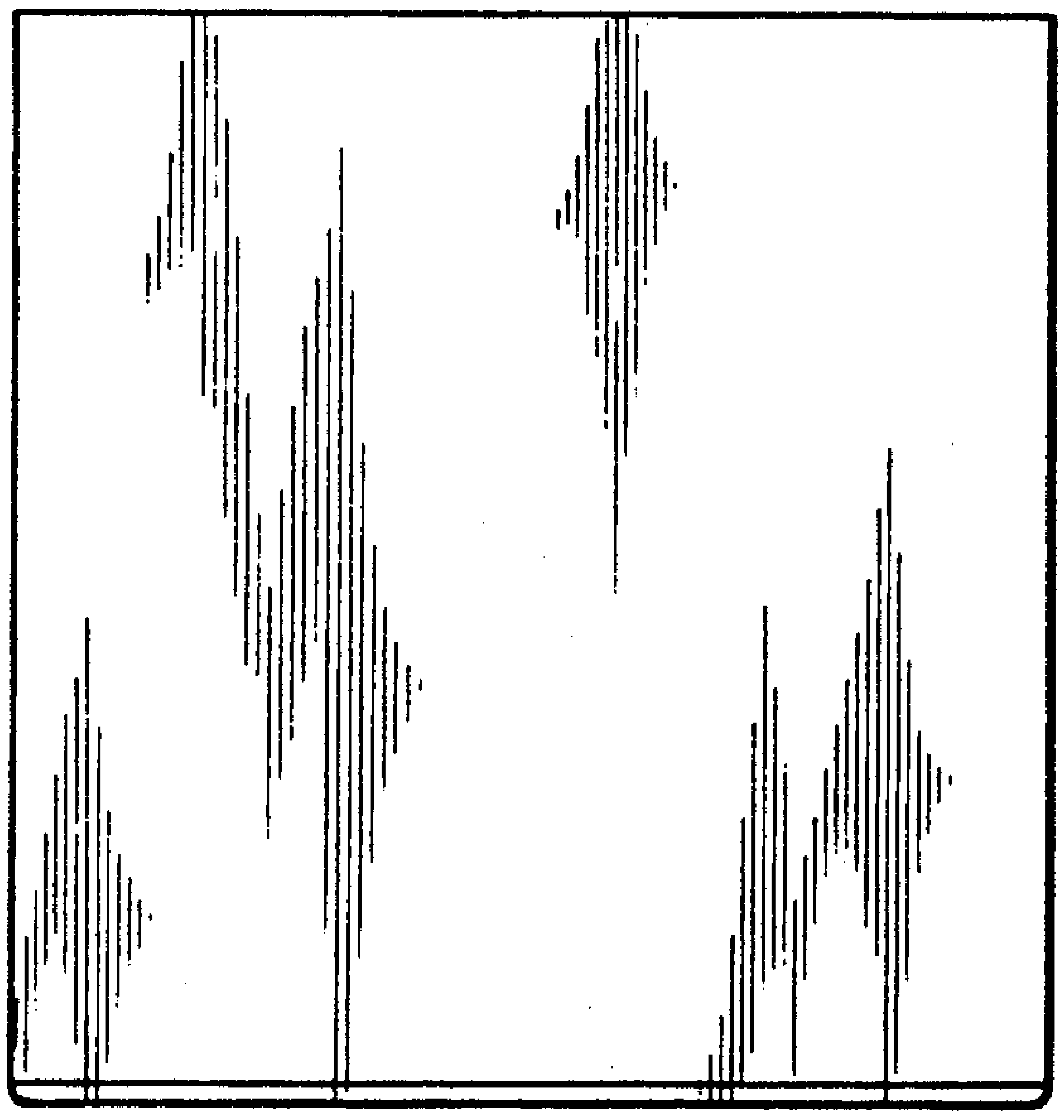

FIG. 4

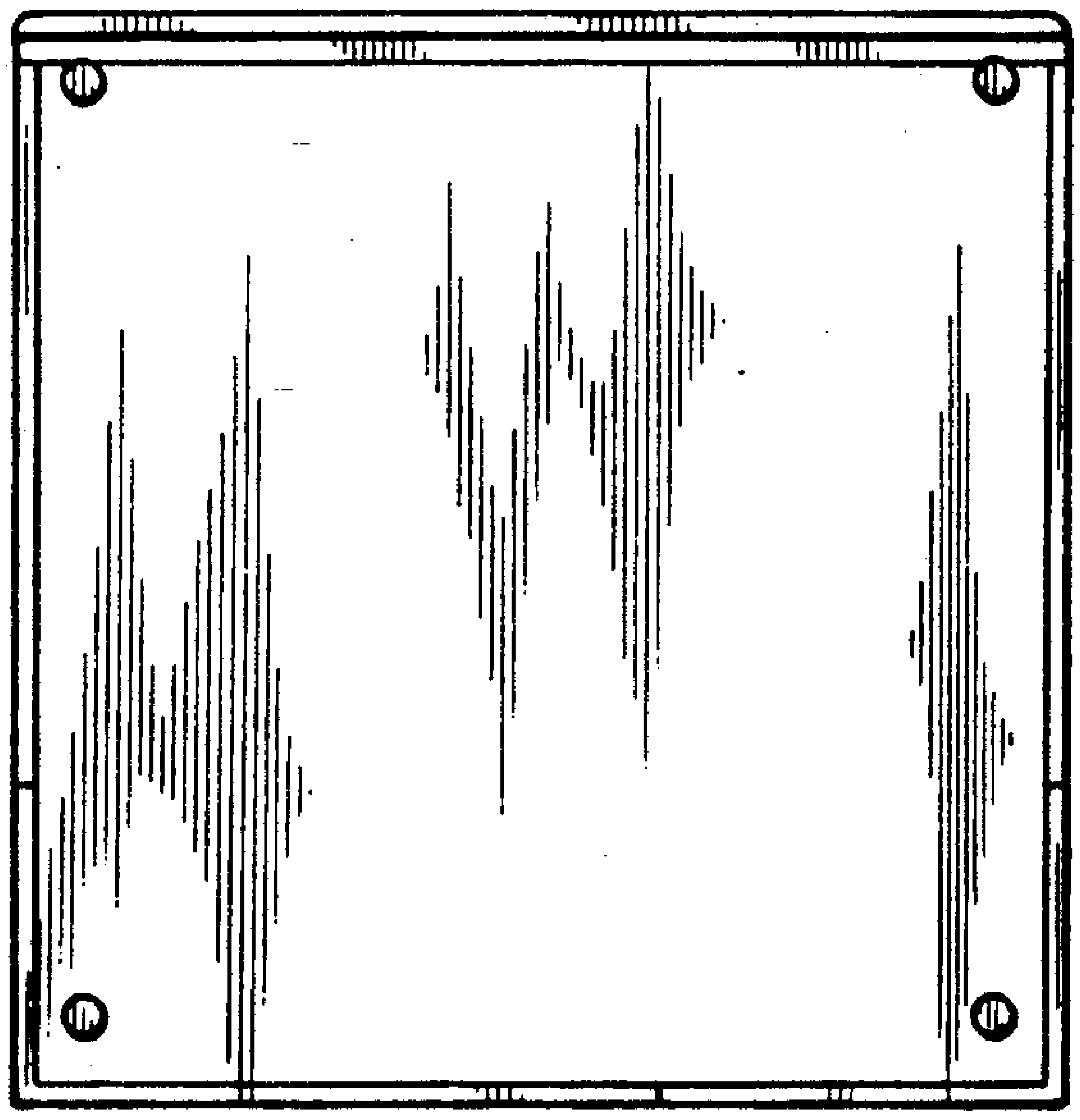

FIG. 5

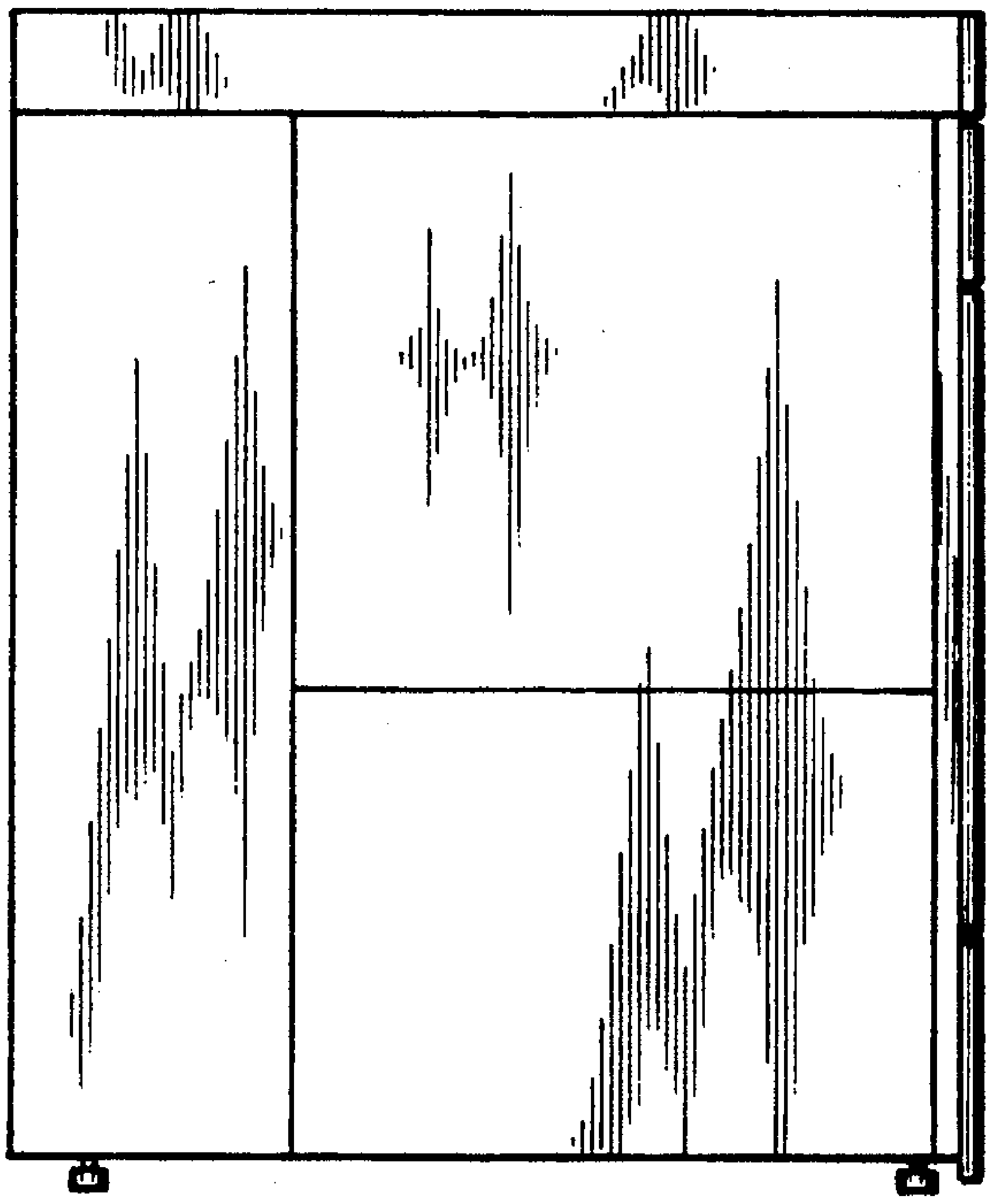

FIG. 6

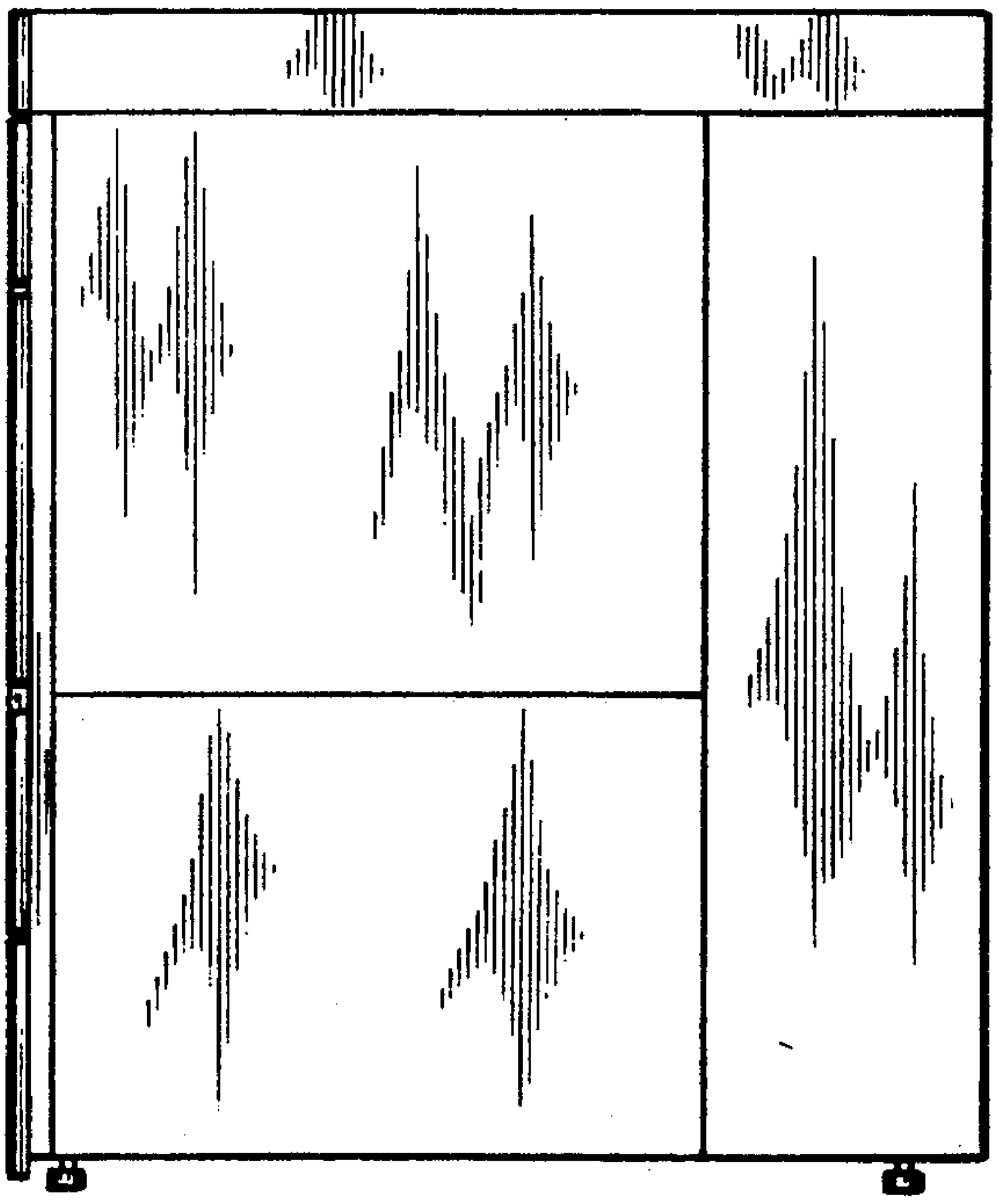

FIG. 7